

**Amendments to the Specification:**

Page 1, please substitute the paragraph beginning on line 1 with the following subtitle and paragraph:

**BACKGROUND OF THE INVENTION**

The present invention relates to a vacuum treatment chamber for generating disk-shaped workpieces with directly bondable surfaces.

Page 8, between lines 2 and 3, insert the following:

**SUMMARY OF THE INVENTION**

Page 13, between lines 13 and 14, insert the following:

**BRIEF DESCRIPTION OF THE DRAWINGS**

Page 14, between lines 11 and 12, insert the following:

**DETAILED DESCRIPTION OF THE DRAWINGS**

Page 16, please replace the paragraph beginning on line 1 with the following amended paragraph:

Especially in the industrial application of the method according to the invention, a magazine 51 is used as the workpiece carrier 51, with the processing chamber according to the invention shown schematically in Figure 1. A plurality of substrates to be processed is stacked therein and connected only by insertion slits on the front and/or rear for the substrates, as well as access slits 51a

additionally provided in the magazine wall. The geometric ratio  $\frac{H}{L}$  relative to the remaining communication openings (access slits) between the substrate surfaces and processing chamber P can then be much smaller than the dark space distance of the plasma discharge maintained in the chamber. The surface processing used according to the invention is performed by the gas containing nitrogen that is excited by the discharge and enters the magazine through the abovementioned openings and slits.